

UNITED STATES PATENT AND TRADEMARK OFFICE
CERTIFICATE OF CORRECTION

PATENT NO. : 6,943,392 B2
APPLICATION NO. : 09/388063
DATED : September 13, 2005
INVENTOR(S) : Agarwal et al.

Page 1 of 1

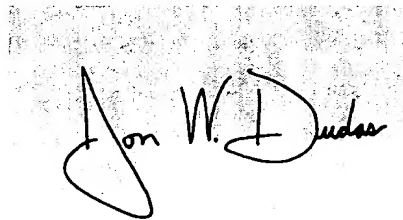
It is certified that error appears in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

Title Page 3, "**References Cited**", "OTHER PUBLICATIONS", Col. 2, lines 1-5,
please delete "Yamamichi, S., et al., ABSTRACT, "Ba +Sr)/Ti Ratio Dependence of
the dielectric properties for (BaSub0Sub.Sub5SrSub0.Sub5)TiO Sub 3 thin Films
Prepare by Ion Beam Sputtering", *Appl. Phys Letters*, col. 64(13), pp. 1644-1646
(1994)."

Col. 8, line 31, claim 27, please insert --tantalum nitride, titanium nitride,-- after
"tungsten nitride,".

Signed and Sealed this

Fifteenth Day of August, 2006

A handwritten signature in black ink, appearing to read "Jon W. Dudas", is written over a light gray rectangular background.

JON W. DUDAS
Director of the United States Patent and Trademark Office